



[10191/3935]

1763

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Inventor(s) : Franz LAERMER et al.  
Serial No. : 10/506,457  
Filed : January 5, 2005  
For : DEVICE AND METHOD FOR ANISOTROPIC PLASMA  
ETCHING OF A SUBSTRATE, A SILICONE BODY IN  
PARTICULAR  
Examiner : Allan Olsen  
Art Unit : 1763  
Confirmation No. : 9990

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, Virginia 22313-1450

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to: Mail Stop Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, Virginia 22313-1450 on:

Date: MAY 7, 2007Signature: Chil W**AMENDMENT TRANSMITTAL AND REQUEST FOR EXTENSION OF TIME  
PURSUANT TO 37 C.F.R. §1.136(a)**

Transmitted herewith for filing in the above-identified patent application is an Amendment in response to the Office Action of November 13, 2006.

Applicants respectfully petition for **three-month extension of time** to respond to the Office Action of November 13, 2006, for which a three-month response period expired on February 13, 2007. The extended period for response expires on May 13, 2007. Please charge the three-month extension fee of **\$1,020.00** and any additional fees to the deposit account of Kenyon & Kenyon LLP, deposit account number **11-0600**. A duplicate copy of this transmittal letter is enclosed for that purpose.

Respectfully submitted,

Date: MAY 7, 2007By: Gerard A. Messina

Gerard A. Messina  
Reg. No. 35,952

05/11/2007 RFEKADU1 00000010 110600 10506457

01 FC:1253 1020.00 DA

KENYON & KENYON LLP  
One Broadway  
New York, New York 10004  
(212) 425-7200  
**CUSTOMER NO. 26646**